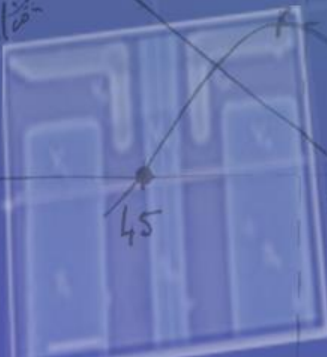
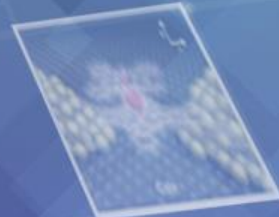


$\frac{1}{158}$
dét. sup. d'analyse
cristalline
réaction



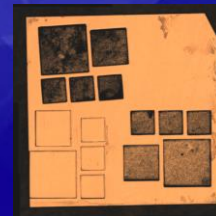
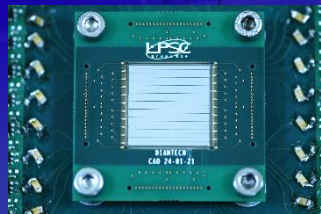
26 5⁻⁶



MICRO/NANO-FABRICATION EXAMPLES :

DIAMOND SENSOR MATRIX

ULTRATHIN DIAMOND MONITOR

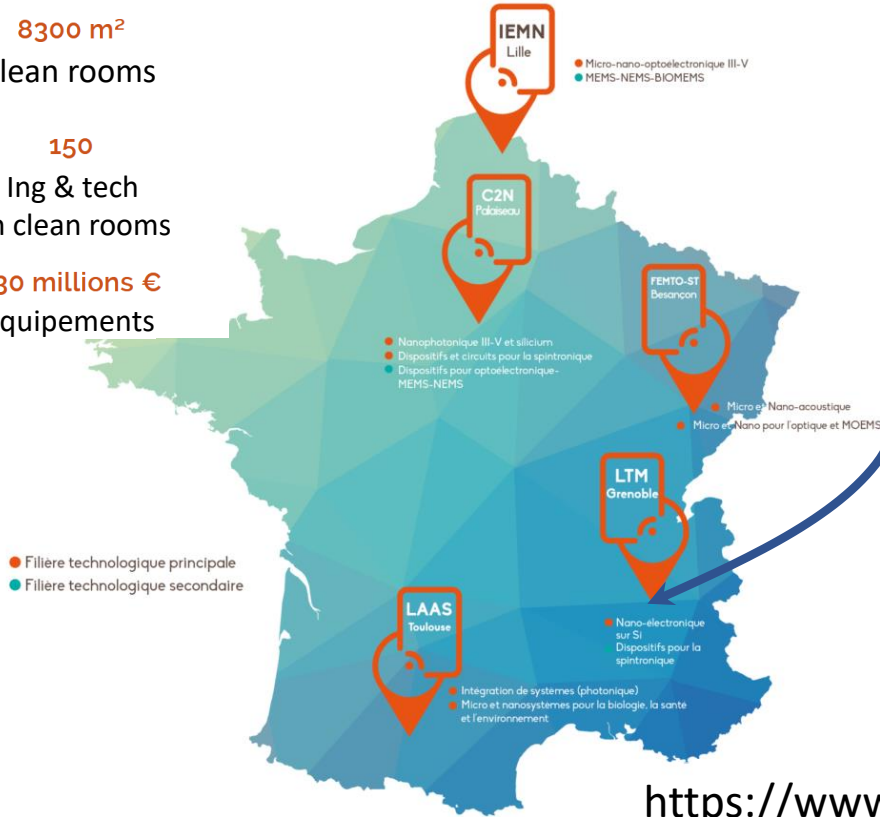


1. NANOFAB A LOCAL CLEAN ROOM AT NÉEL IN RENATECH NETWORK
2. CONTEXT: DIAMOND DEVELOPMENTS - MULTIDISCIPLINARY ACTIVITIES
3. WHY GO FROM MACRO TO NANO TWO WAYS
4. FISTR EX : DIAMOND SENSOR MATRIX BEAM MONITORING IN RADIOTHERAPY
5. SECOND EX : ULTRA-FINE DIAMONDS AND THEIR PROBLEMS
6. NANOFAB PORFOLIO

8300 m²
Clean rooms

150
Ing & tech
in clean rooms

130 millions €
equipements



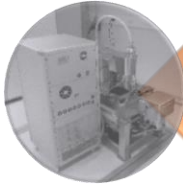
RENATECH is the French academic network for cutting-edge equipment in the field of micro and nanotechnologies, led by the CNRS.

Our aim is to develop, maintain and supply a competitive infrastructure for research and R&D in micro- and nanofabrication in France.

We work with both academic and industrial customers.

<https://www.renatech.org/>

TECHNOLOGIES



LITHOGRAPHY

- Electron beam : 30/80kV
(SEM LEO1530 & NB5)
- Optical UV
(UVKUB-Smart Print-lithoLASER)



COATING DEPOSITION :

- Joule effect or electron gun
- Plasma spraying
- UHV



ETCHING :

- RIE (O_2 , SF_6 , CHF_3 , CF_4 , Ar)
- IBE (Ar)
- Chimique (XeF_2 , KOH, ...)
- FIB

SCIENTIFIC FIELD

- MECHANIC
- THERMIC
- **BIOLOGY**
 - Coponent/sensors
 - innovative radiotherapies is the objectives of radiobiology
- ELECTRONIC
 - Captors/components
 - Plasmonic (FIB)
 - Quantum engineering
 - Power electronics (diamond)
 - ...



POSTER SESSION

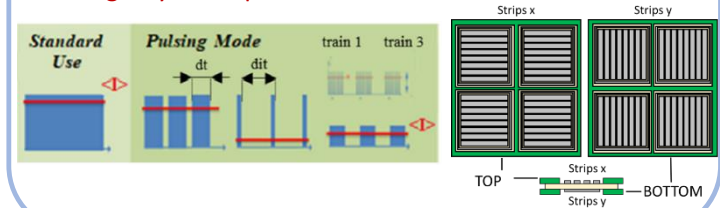
Medicals Physics

- **Beam monitoring in radiotherapy** (position/time labeling/counting)
- **on-line monitoring of ion microbeams**
 - Large area ($>1\text{cm}^2$)
 - High counting rate (100 MHz)
 - Good sensitivity and high dynamic range (detection of single particles in bunches up to 1010 particles in trains for Flash therapies)
 - Resistance to irradiation

ANR DIAMMONI 2020-2024 LPSC / SUBATECH/ARRONAX

ANR-DIAMMONI ML Gallin-Martel et al.

High-dynamic pulsed-beam diamond monitor



on-line monitoring of ion microbeams

LPSC / LP2i / IRSN

DEFI Diams Thèse de C. Léonhart

AIFIRA / MIRCOM



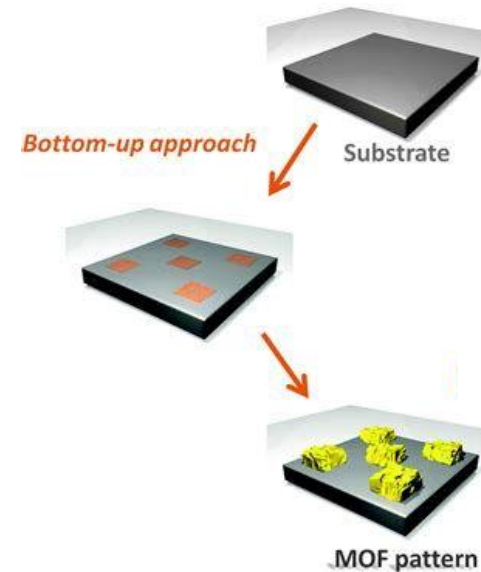
Diamond $4\text{mm}^2 \times 50\mu\text{m}$

window $500\mu\text{m}^2$, 1 to $2\mu\text{m}$ thin

Metallized electrodes for diamond polarization and signal reading

Bottom-up

- Building nano-objects from individual building blocks (atoms, molecules)
- Self-organisation



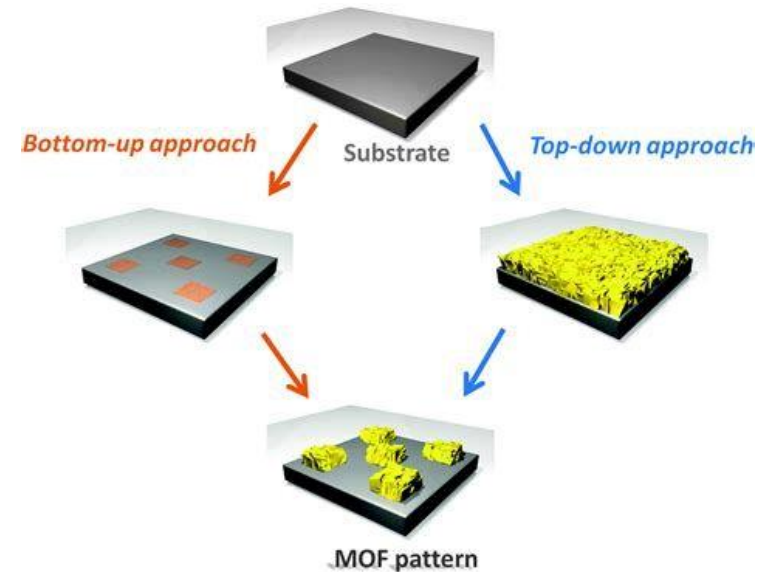
Ex : Preparation of organometallic structures

Bottom-up

- Building nano-objects from individual building blocks (atoms, molecules)
- Self-organisation

Top-Down

- Shaping substrates
- Reducing the size of the "macroworld"
- Lithography



Ex : Preparation of organometallic structures

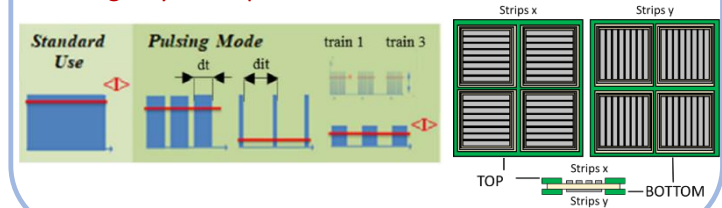
Medical Physics

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ANR DIAMMONI 2020-2024 LPSC / SUBATECH/ARRONAX

ANR-DIAMMONI ML Gallin-Martel et al.

High-dynamic pulsed-beam diamond monitor



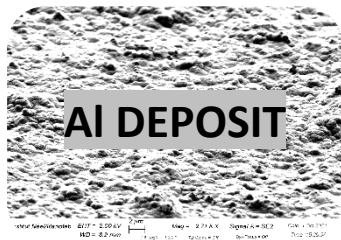
8. DIAMMONI : un détecteur pour le monitoring en ligne de très hauts flux pour le cyclotron d'ARRONAX

👤 Robin Molle (LPSC - Grenoble)

🕒 26/06/2024 09:30

📁 Semiconductors

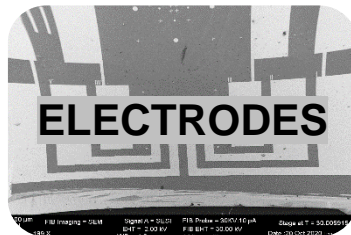
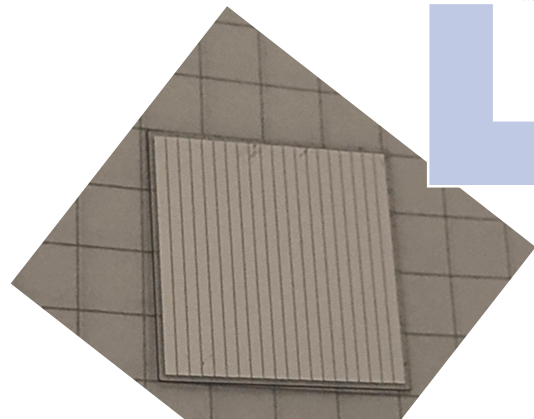
Latifa Abbassi (Institut Néel)



- Optical microscope observation, roughness, etc...
- Cleaning acid mixture
- Deposit quality control

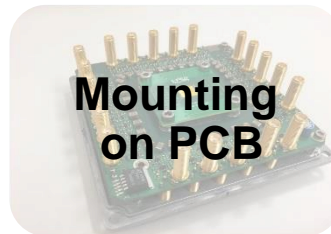
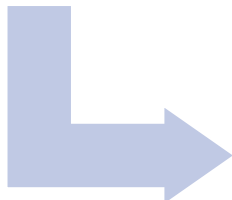
state of the surface

Melvyn Reynaud (LPSC)



- Resist spin control
- Insulating the resist with a laser
- Developpement
- Chemical etching

Write resolution
Sample size

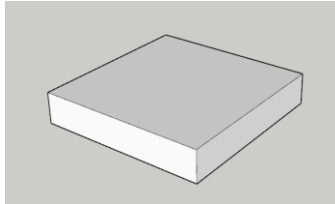


- Mechanical
- Assembly
- Bonding

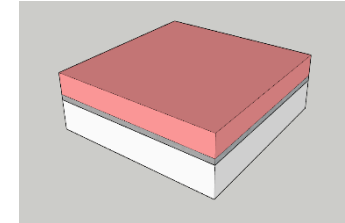
Pixelated diamond sensors
- 19mm²
- 20 tracks 0,9mm spaced 0,05mm, accuracy 0,01mm



Diamond substrat

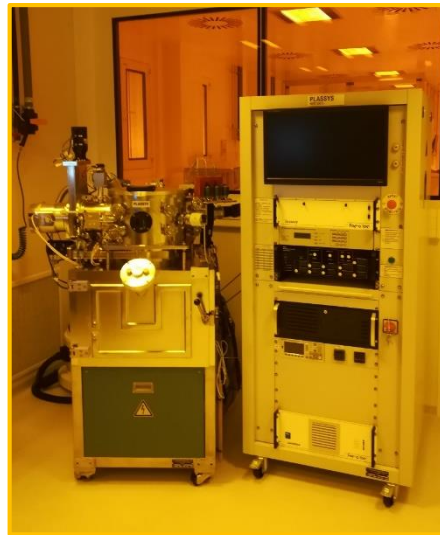


Coat 100nm Aluminium + **ZPN resist 500/800nm**



Electron gun evaporator MEB550S PLASSYS

- Vacc (4.10-8mBar)
Turbo + Cryo
- 8 available materials



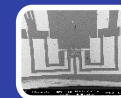
Spin Coater

- Clean room and laminar flow (dust)
- Under hoods for toxic chemical



Spreading of resin by rotation (1000 to 10000 rpm)

Annealing required to evaporate the solvent



- Major difficulties for diamonds :

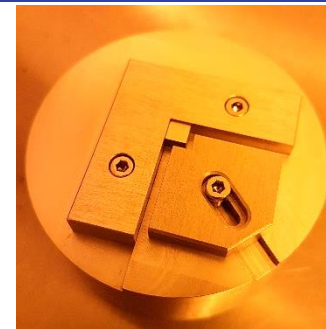
- Transparency
- Shape and thickness: handling and even spreading of the resin



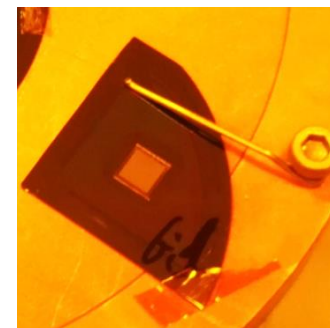
➤ Classical circular wafer 2" (50,8mm)



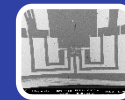
➤ 10mm² to 4 mm² square diamond



New sample holder
to limit edge effects

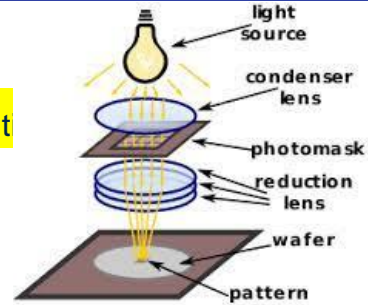


"gluing" to a support substrate
for diamonds < 200μm thick

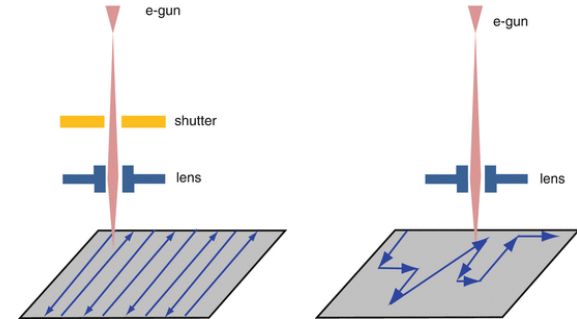


– **WITH RESIST** (photon-électron sensit)

- Optical lithography
- Electron lithography
- Ion beam lithography



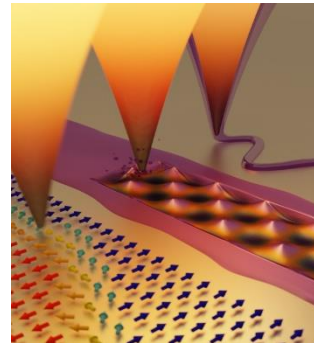
Projection photolithography through a mask



**Direct-write lithography
LASER-eBeam**

– **WITHOUT RESIST**

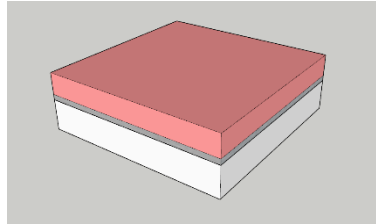
- Ion beam (FIB)
- Near field (AFM,STM)



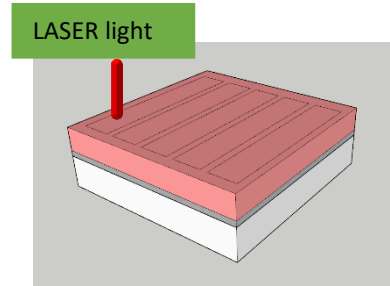
Direct-write lithography with local probe



Transfer a design



LASER lithography
direct writing

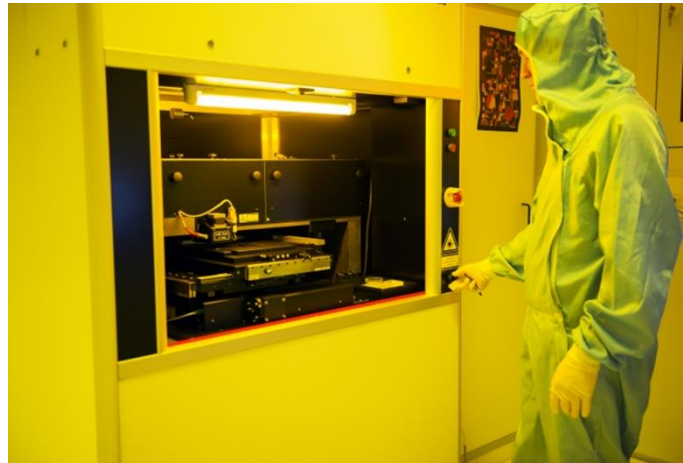


2 types of resists:

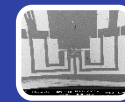
- **Positive**
light makes the resist soluble
- **Negative**
light makes the resist insoluble

LASER lithography Heidelberg DWL 66S

- Resolution 1 μ m
- 160mm max writefield
- direct writing = throughput

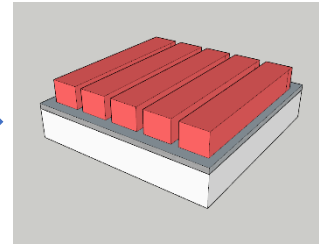
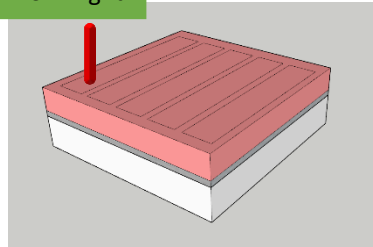


**LASER spot coming out of the
writing head lens**

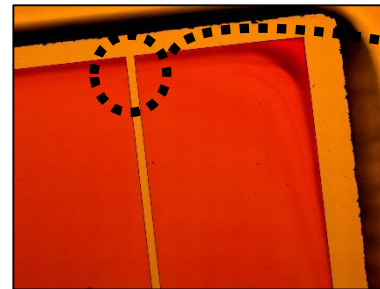
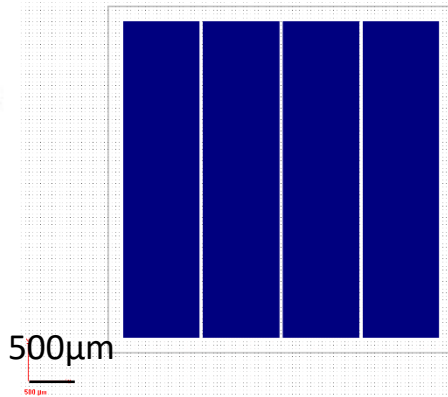
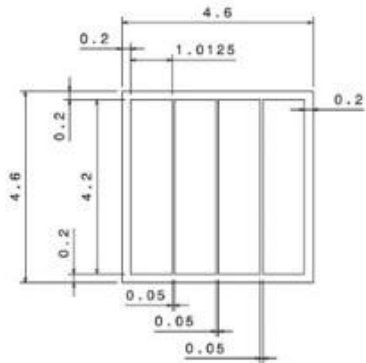


Transfer a design

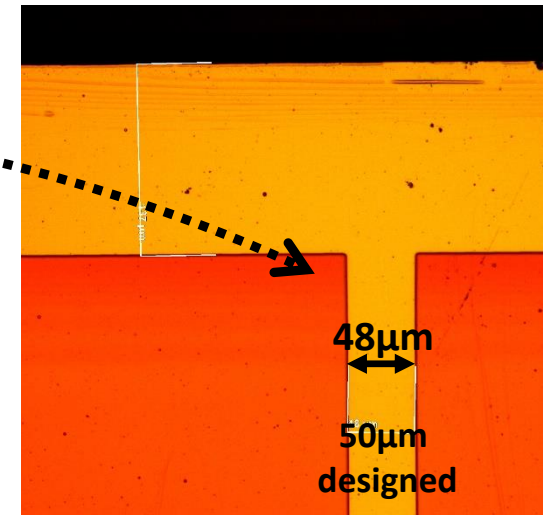
LASER light



Sample size !!!!



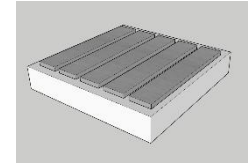
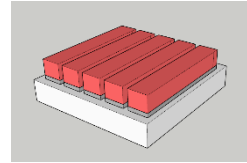
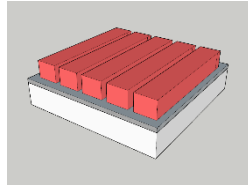
Drawing transferred in the resist
onto the sample, after exposure
and development



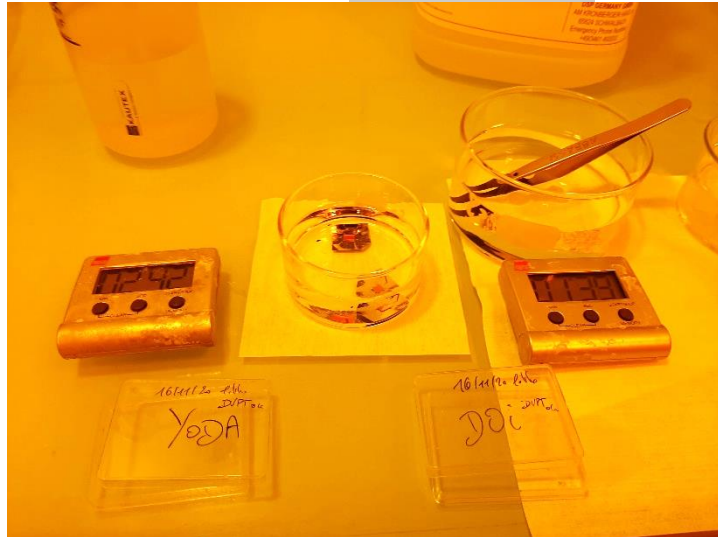
Conversion of CAD drawings into
"GDS" lithography language



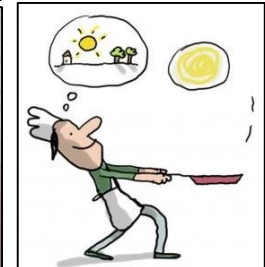
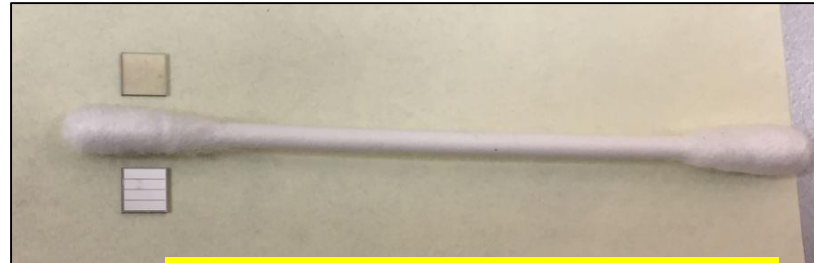
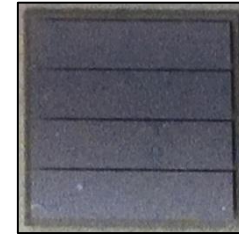
Aluminium etching (20nm/min)



Resist removed



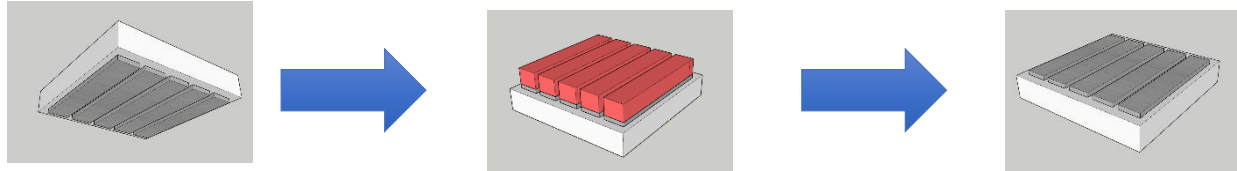
5 x 5 mm²
1 x 4 traks
the trick is done
on one side



And now to do the second side

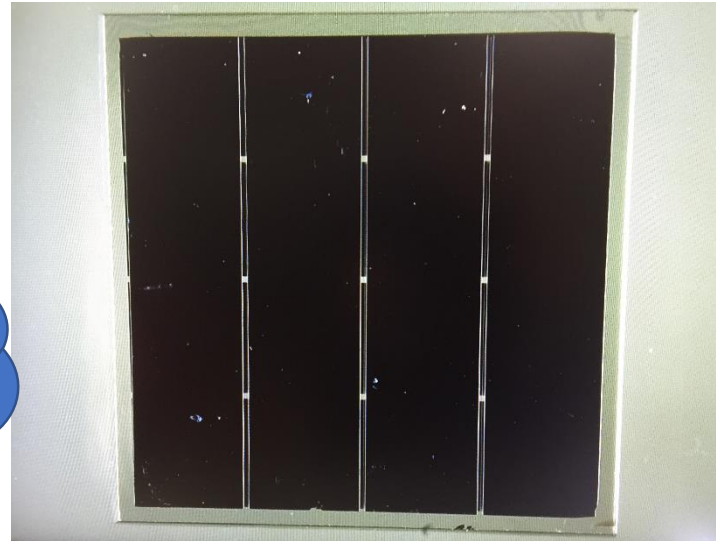


Bis repetita !!!!! Without damaging the rear face

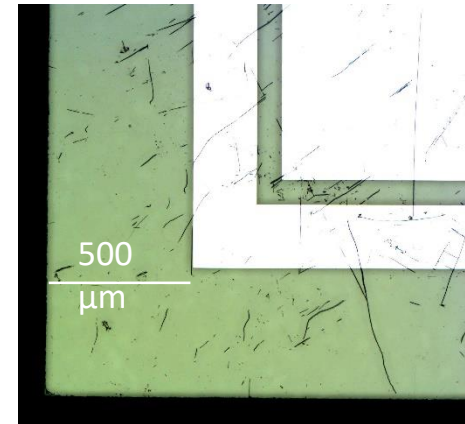
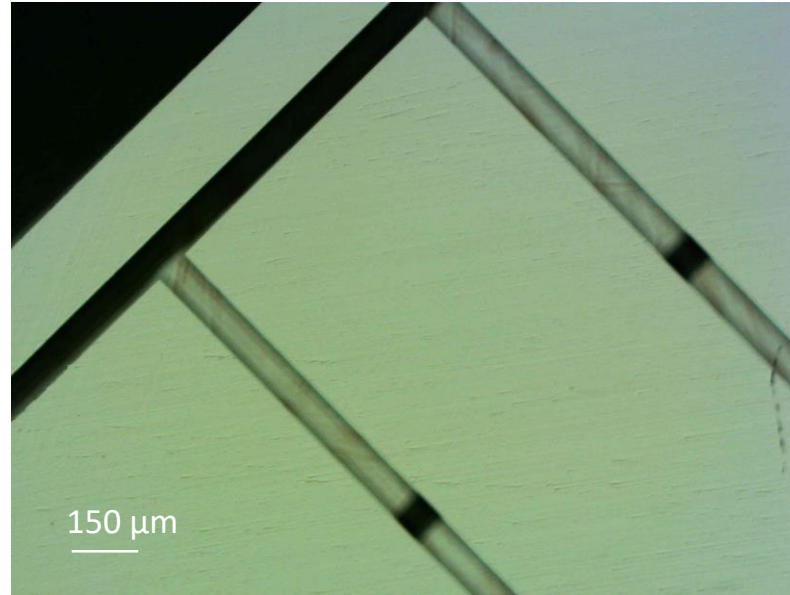
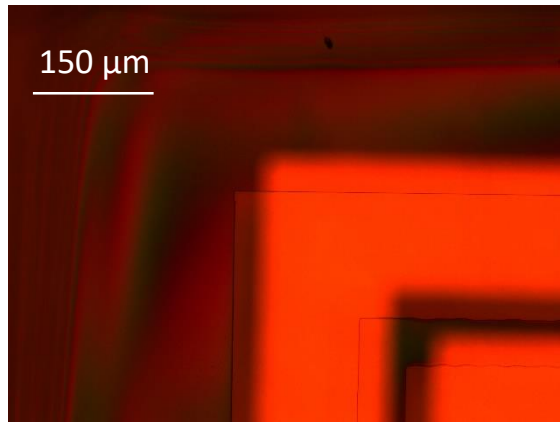
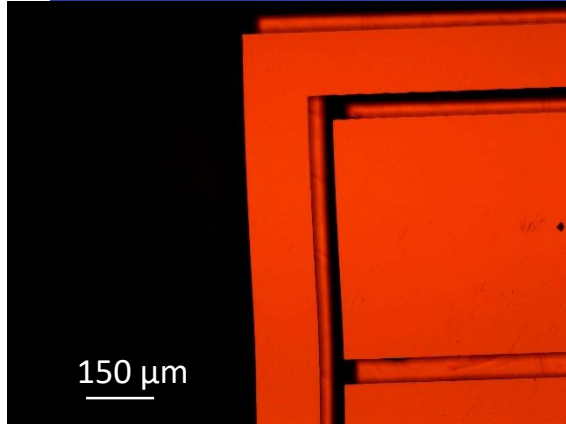


SCRATCH !!!
Protected and glued
on the back side

ROBUST PROCESS:
do not engrave
the back side

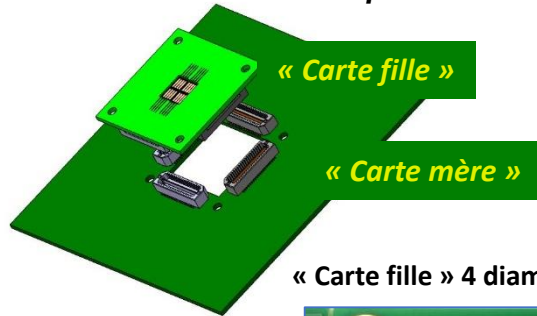


5 x 5 mm²
2 x 4 tracks at 90°
2 sides

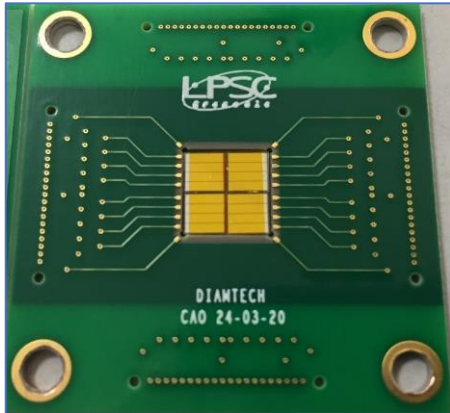




3D Conception



« Carte fille » 4 diamonds sc – 32 channels



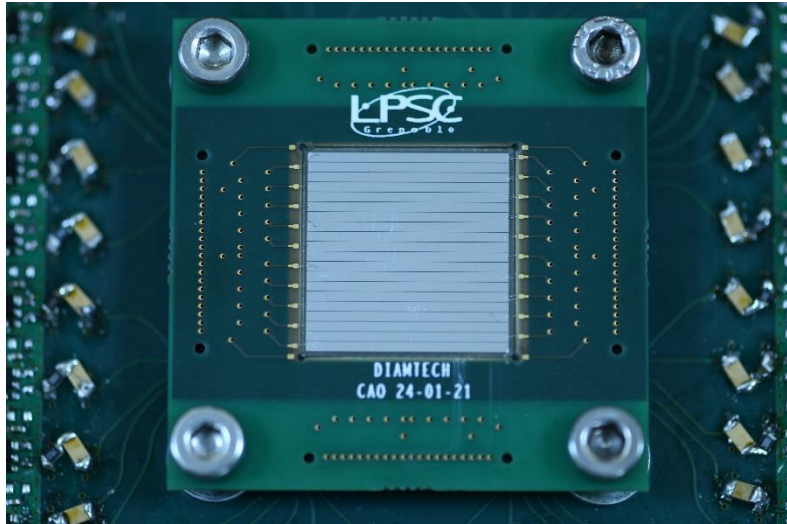
Advantages:

- 1 “carte fille” per diamond
- Assembly quick changeover (simply remove “carte fille”)
- Reuse of the same amplification channels

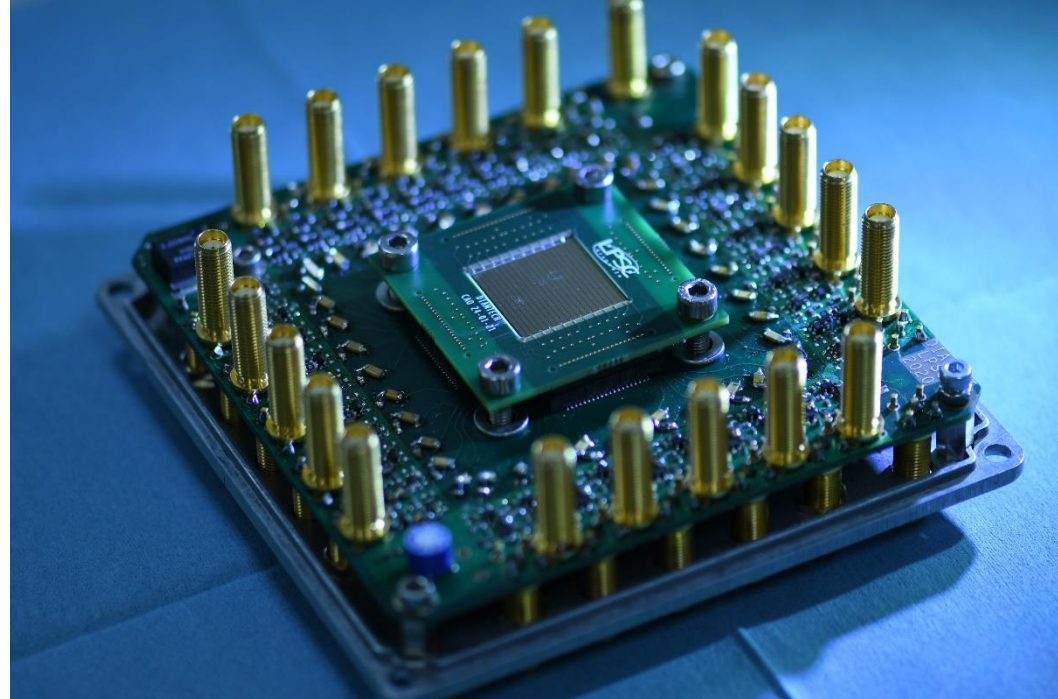


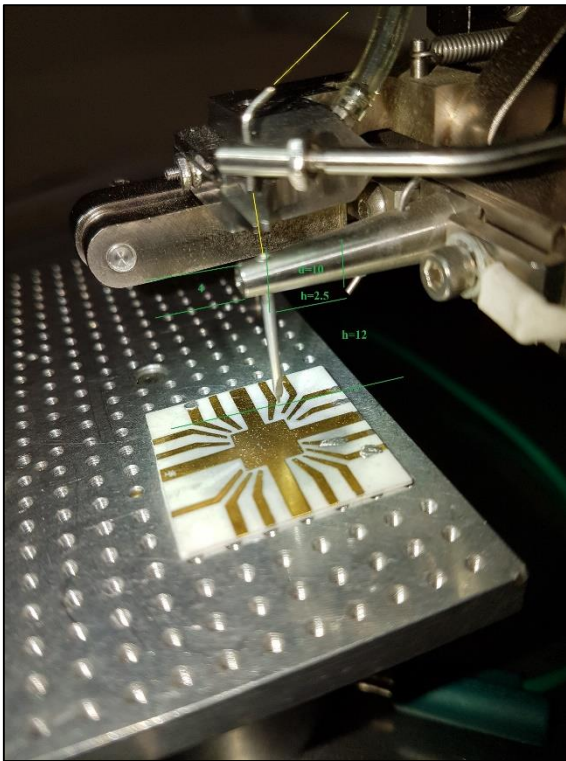
- Hodoscope 4 Diamonds (carte mère & fille 32 channels)
- sc 9.6 x 9.6 mm², 32 strips

Jean-Luc Bouly, Germain Bosson, Marc Marton, J-F Muraz (LPSC)

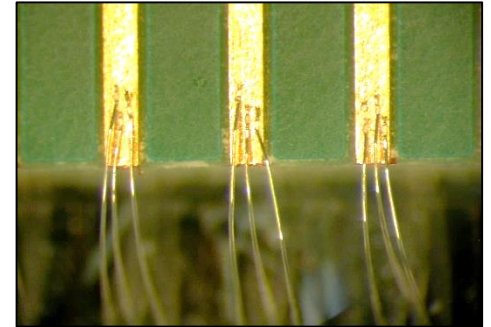
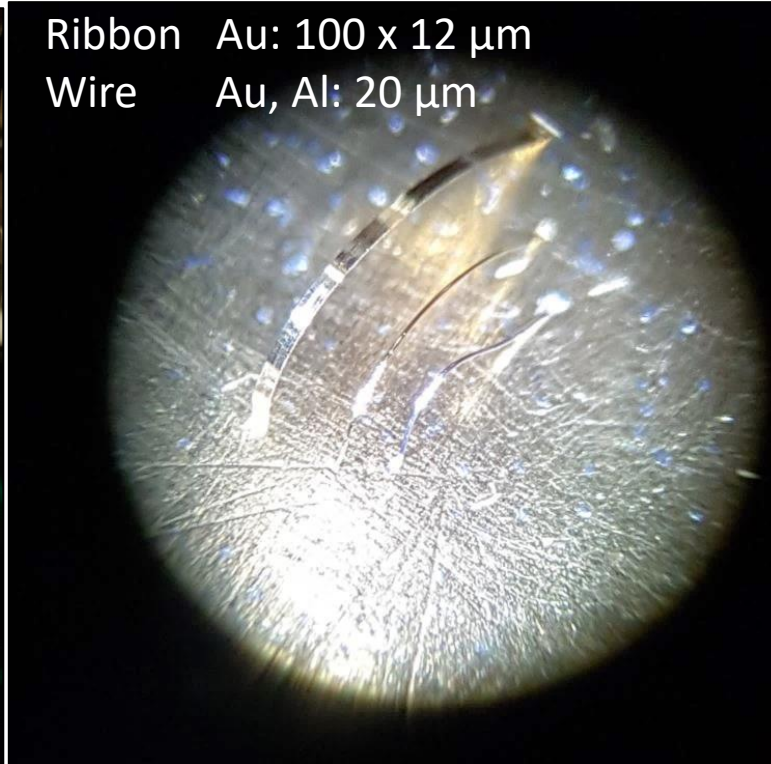


*Hodoscope 1 Diamond
(carte mère & fille 40 channels)*





Ribbon Au: 100 x 12 μm
Wire Au, Al: 20 μm



Manual operation !!!
Under binoculars



Thierry CROZES (Institut Néel)

Medicals Physics

- **Beam monitoring in radiotherapy** (position/time labeling/counting)
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 - Large area ($>1\text{cm}^2$)
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on-line monitoring of ion microbeams

LPSC / LP2i / IRSN

DEFI Diams Thèse de C. Léonhart

AIFIRA / MIRCOM



Diamond $4\text{mm}^2 \times 50\mu\text{m}$
 window $500\mu\text{m}^2$, 1 to $2\mu\text{m}$ thin
 Metallized electrodes for diamond polarization and
 signal reading



DEFI Diams Thèse de C. Léonhart

Why ultra-thin?

- ✓ To have a minimum quantity of material before the biological environment
- ✓ And to limit disturbances: loss of energy and spatial deviation

Diamond scCVD
Electronical or optical grade

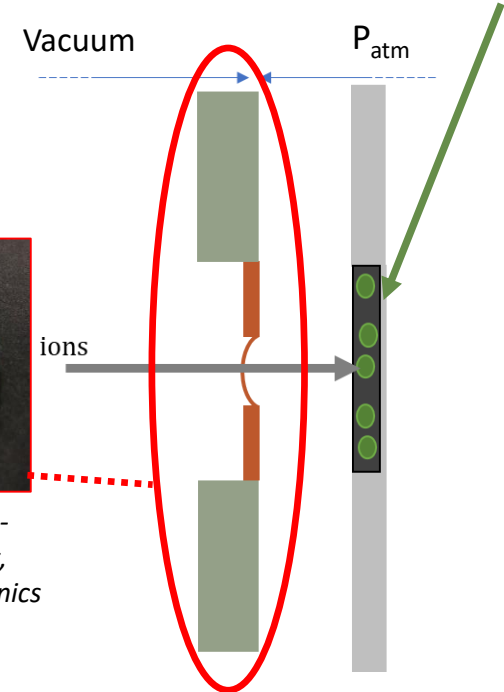


Window $500\mu\text{m}^2$, 1 to $2\mu\text{m}$ thin
Metallized electrodes for diamond polarization and signal reading



*DéfiDiams sample holder -
Produced by the Detector,
Instrumentation and Electronics
Departments at LPSC*

Diamond window placed on its sample holder upstream of the biological medium.



Diamond scCVD

Electronical or optical grade

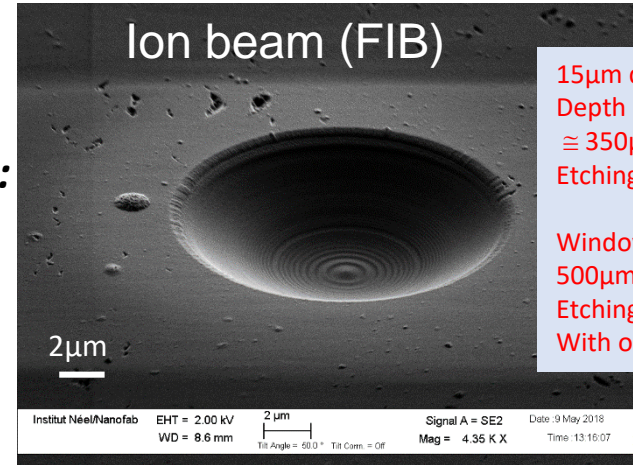


Window $500\mu\text{m}^2$, 1 to $2\mu\text{m}$ thin

Metallized electrodes for diamond polarization and signal reading

1. MECHANICAL ETCHING :

- Very High precision
- Too low Throughput

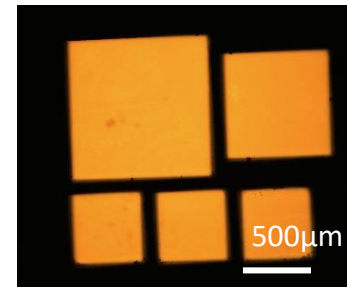


15 μm diameter
Depth around $4\mu\text{m}$
 $\cong 350\mu\text{m}^3$
Etching $\cong 15\text{min}$

Windows
 $500\mu\text{m}^2 \times 49\mu\text{m}$ depth
Etching $>8000\text{H}$
With our FIB

2. CHEMICAL REACTIVE ETCHING :

- Very high Throughput
- Large surface (independent)
- Find a hard mask

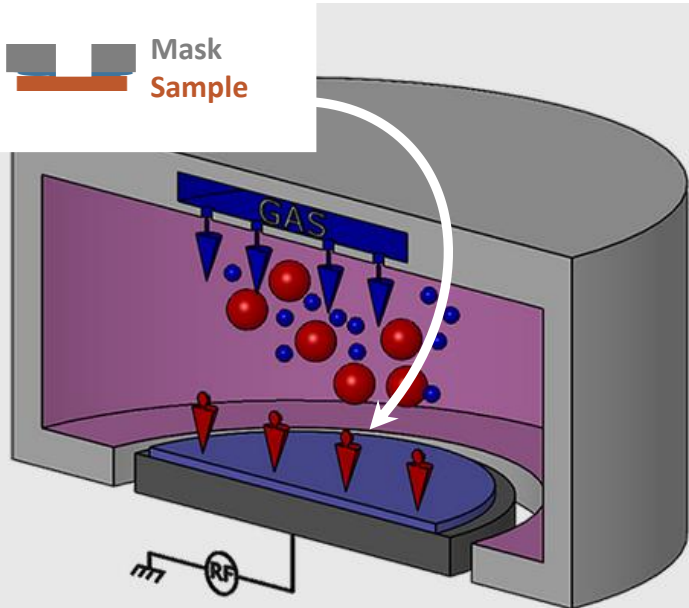


Diamond etching mask

Windows
 $1000/750/500\mu\text{m}^2$

Principle of Reactive Ion Etching

Mask
Sample



Recipe : CF_4 30sccm + O_2 40sccm / 150mT / 280W

<https://corial.plasmatherm.com/en/technologies/reactive-ion-etching-rie>



RIE machine on the Nanofab platform (PLASSYS)



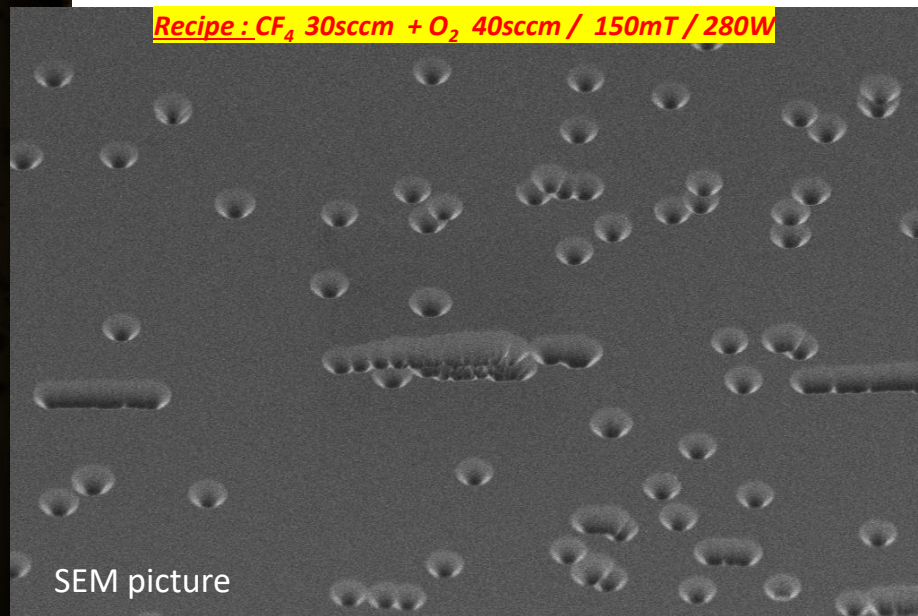
!!! Each black dot on the surface is a hole about 1 μm deep !!!

4h etching
19,2 μm depth

=> around 80 nm/min

Less than half the target!

Recipe : CF₄ 30sccm + O₂ 40sccm / 150mT / 280W



SEM picture

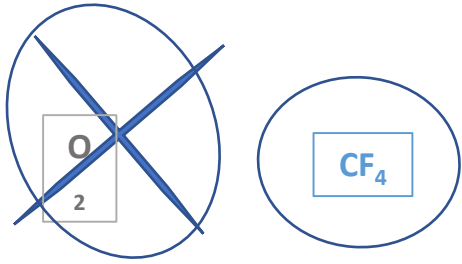
Institut Néel/Nanofab

EHT = 2.00 kV
WD = 6.1 mm

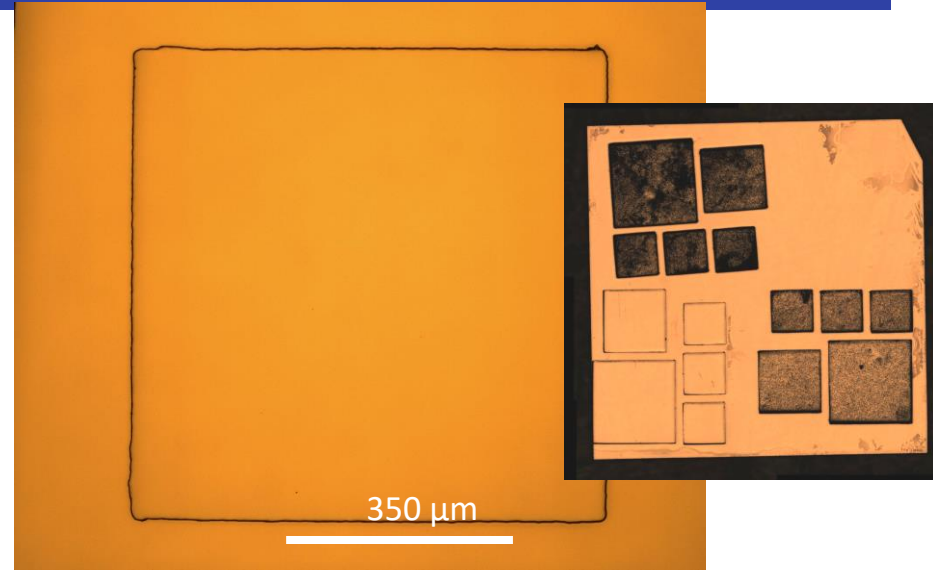
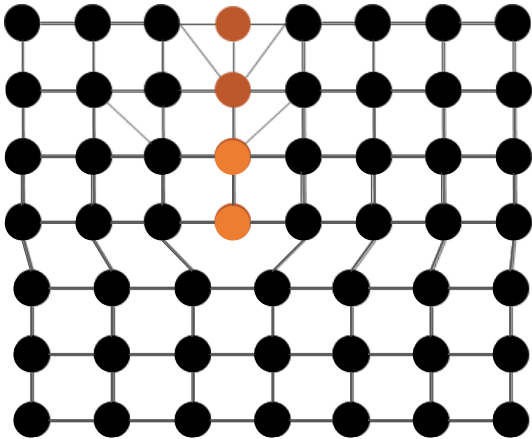
2 μm
H

Signal A = InLens
Tilt Angle = 45.0° Mag = 1.56 KX

Date :25 Jan 2024
Time :11:28:45

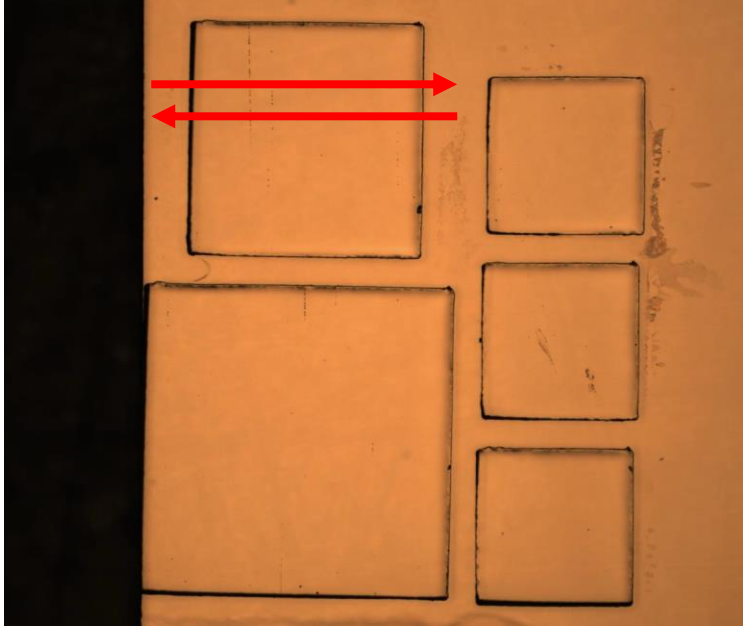


CF₄ 50 sccm
10 mTorr
20°C (chiller)
400 W RF + 1600 W ICP
OXFORD via PTA

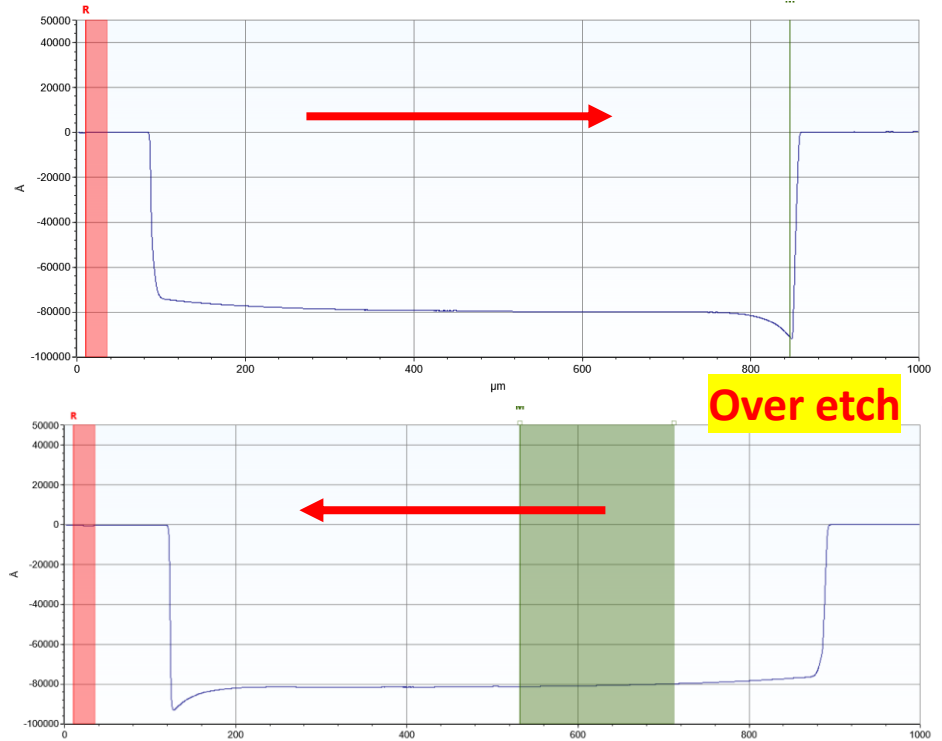


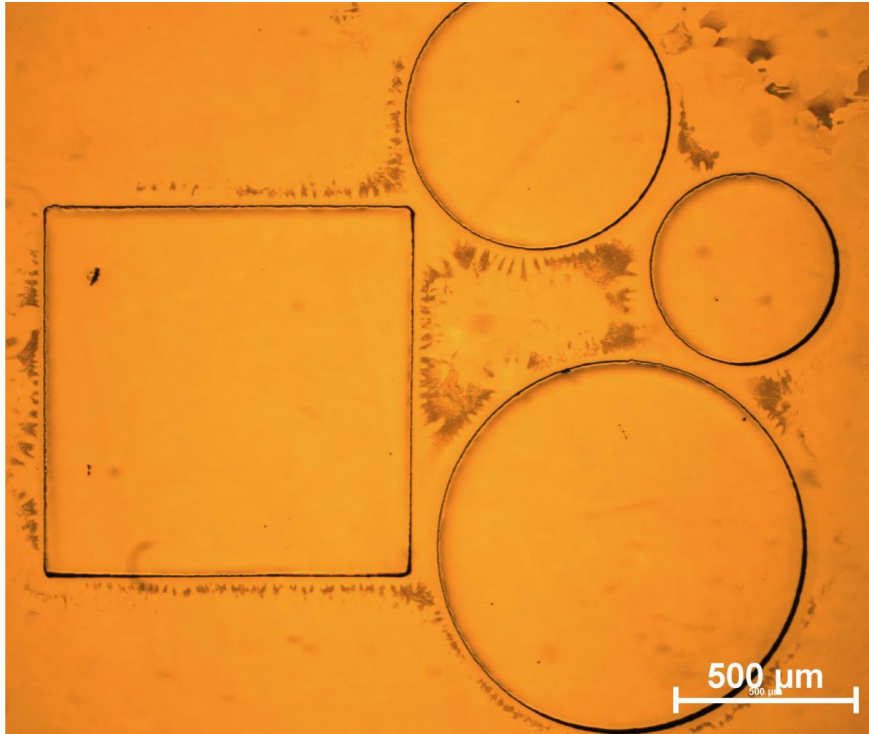
- Etch rate slower without O₂, but no etch pit formed.
- RiE-ICP more powerful = increase the rate etch
- Recipe also validated for longer burn times.

Thomas Charvolin, PTA LTM



Step height: 8.0 μm Speed: 133 nm/min





To be continued

The thinning of the diamond is even less obvious than expected:

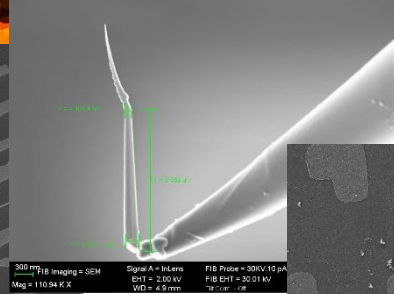
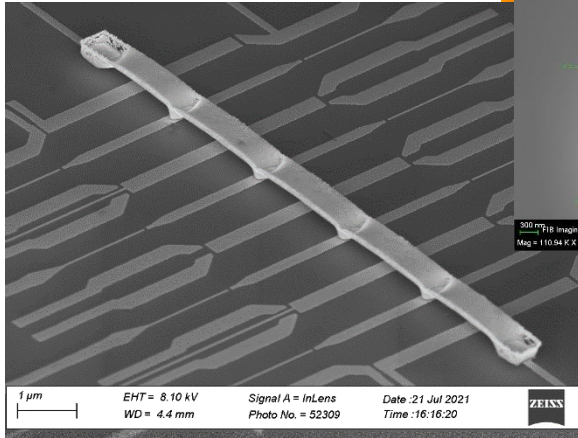
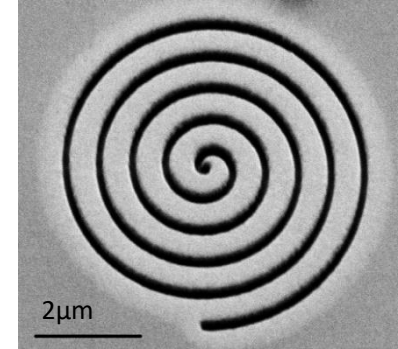
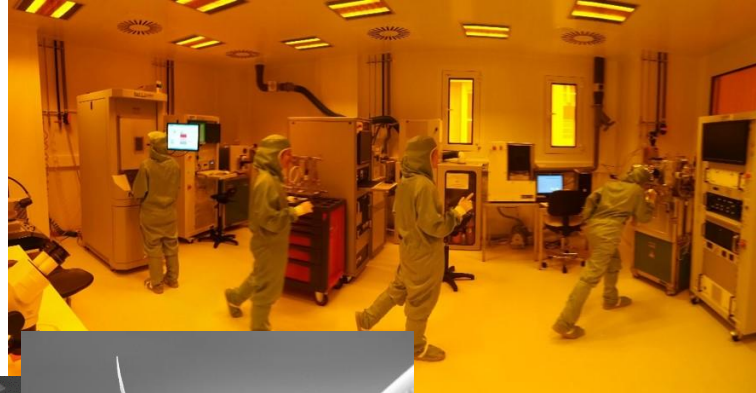
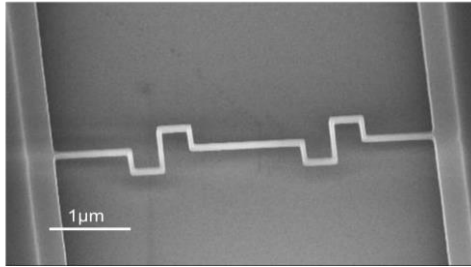
- ❑ Surface defects are disruptive to detection and could puncture the window !!!
- ❑ A better etching recipe, without oxygen, avoids these problems but requires a much longer etching time.
- ❑ The use of a polycrystalline diamond etching mask for the patterns has been validated.

Diamond scCVD
Electronical or optical grade



Window $500\mu\text{m}^2$, 1 to $2\mu\text{m}$ thin
Metallized electrodes for diamond
polarization and signal reading

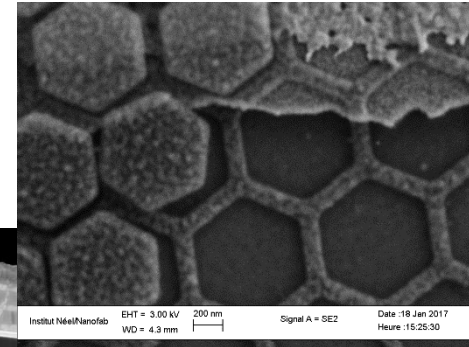
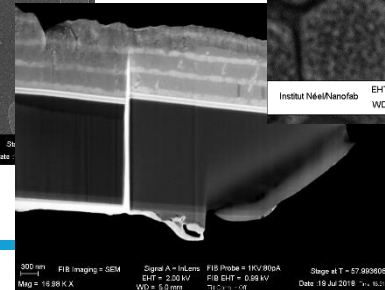
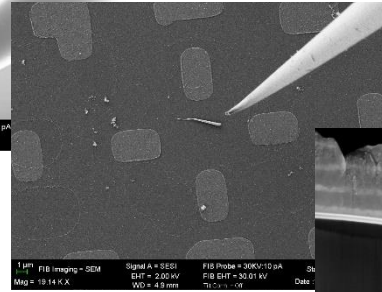
- Production of the first prototype expected in the next few months.
- This was followed by beam tests on the AIFIRA and MIRCOM lines to characterize the detector (thickness, response) and the impact on the beam.



300 MPa FIB Imaging - SEM
Mag = 110.94 K X

Signal A = InLens
EHT = 20.0 kV
WD = 4.6 mm

FIB Probe = 30KV:10 pA
FIB EHT = 30.01 kV
FIB WD = 4.6 mm



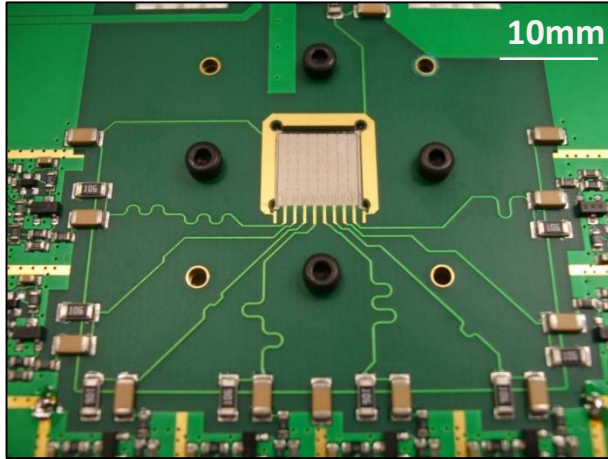
Diamond scCVD

Electronical or optical grade



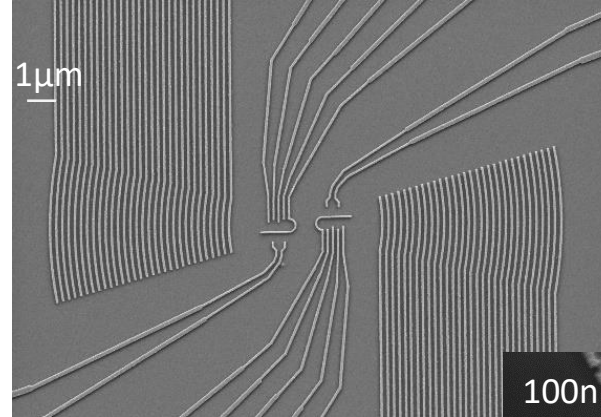
Window $500\mu\text{m}^2$, 1 to $2\mu\text{m}$ thin
Metallized electrodes for diamond
polarization and signal reading

Montage sur PCB, diamant 10x10 mm²

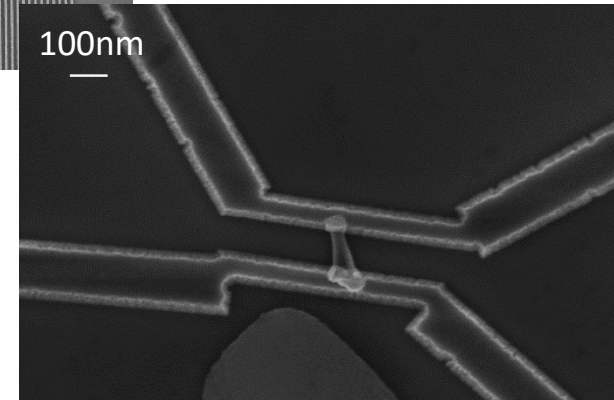


/ 10 000

-Ingénierie quantique : ligne sub μm haute densité /e-beam



- NanoPhysique :
Mesure électrique de nanofil SiC



- Réduire les dimensions du « macromonde »
- Densification des composants actifs

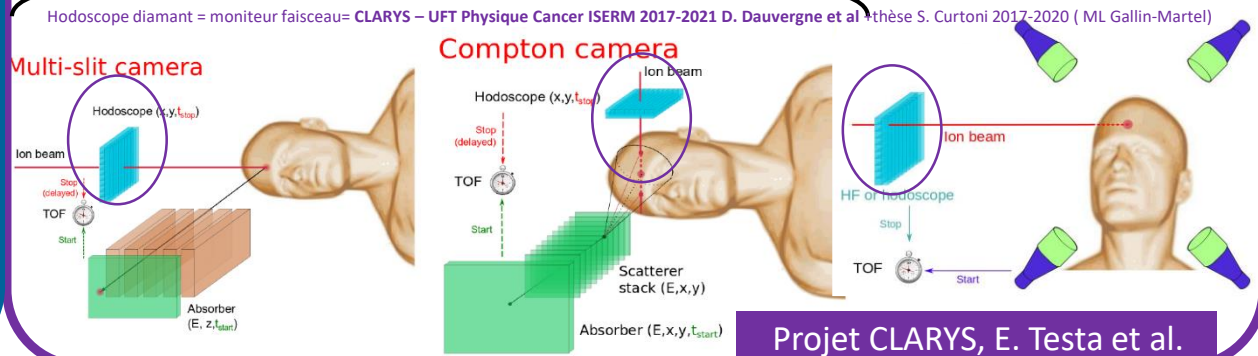
Contexte : développements diamants - activités multidisciplinaires

Physique Médicale

- **Monitoring faisceau en radiothérapies** (position/étiquetage temporel/comptage)
 - Grande surface (>1cm²)
 - Fort taux de comptage (100 MHz)
 - Bonne sensibilité et grande dynamique (détection de particules uniques dans des bunchs jusqu'à 10¹⁰ particules dans des trains pour les thérapies Flash)

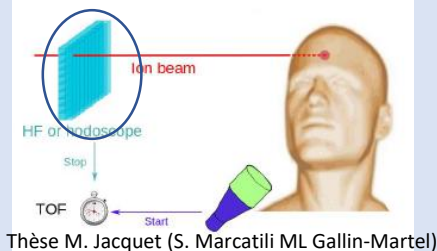
Prompt Gamma Imaging

Thèse O. Allegrini (E. Testa, JM Letang INSA CREATIS)



Projets CLARYS, E. Testa et al.

Prompt Gamma Timing

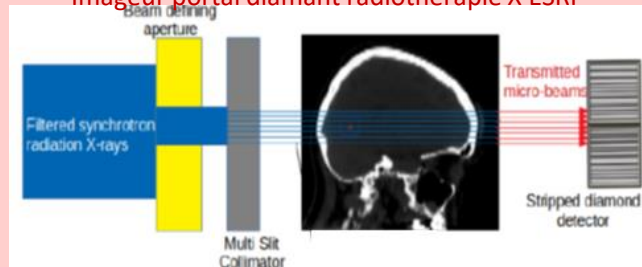


Hodoscope diamant

Projet TIARA physique cancer INSERM 2020-2023 S. Marcatili et al.

Projet R&T DIAMTECH ML Gallin Martel (LPSC) A. Guertin (SUBATECH) et al.

WP1 = IDSYNCHRO IN2P3 / UGA - INSERM
IDSYNCHRO J-F Adam et al
Imageur portal diamant radiothérapie X ESRF

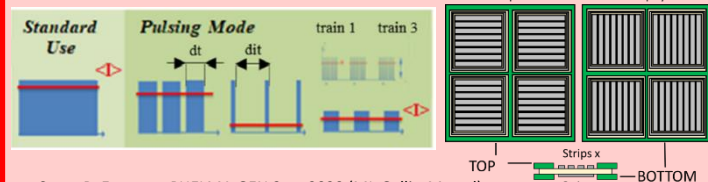


Thèse N. Rosuel 2018-2021 (D. Dauvergne JF Adam UGA-INSERM)
Apprentissage élève ingénieur PHELMA Grenoble INP L. Tribouilloy (L Gallin-Martel)

WP2 = ANR DIAMMONI 2020-2024
LPSC / SUBATECH/ARRONAX

ANR-DIAMMONI ML Gallin-Martel et al.

Moniteur faisceau pulsés grande dynamique en diamant



Stage P. Everaere PHELMA GEN 3 en 2020 (ML Gallin-Martel)
Stage R. Molle PHELMA GEN 3 en 2021 (ML Gallin-Martel)
Thèse X 2021-2024 (LPSC, SUBATECH)